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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Hideshi NISHIKAWA et al.

Serial No.: 10/809,712

Filed: March 26, 2004

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Art Unit: 1775

Examiner: Speer, T.

For: SILICON ANNEALED WAFER AND SILICON EPITAXIAL WAFER

AMENDMENT

Commissioner of Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the outstanding Office Action dated July 18, 2006, please amend the application as follows: